

EAST - 10600000.wsp:1

File View Edit Tools Window Help

Drafts
 Pending
 Active
 L3: (330) (((light\$3 near doped near drain
 L4: (294) (((light\$3 near doped near drain)
 L5: (285) 4 and insulat\$3
 L6: (121) 5 and (source adj electrode and
 L7: (16) 6 and interlayer adj dielectric
 Failed
 (0) (((light\$3 near doped near drain) and (
 Saved
 (13266) (light\$3 near doped near drain) or
 (1879) (((light\$3 near doped near drain) or
 (589) (((light\$3 near doped near drain) or
 (0) (((light\$3 near doped near drain) or L
 (546) (((light\$3 near doped near drain) or
 (2) ("6624473").PN.
 Favorites
 Tagged (0)
 UDC
 Queue
 Trash

DBs: USPAT: EPO: JPO: DERWENT: IBM: TDB

Default operator: OR

Plurals
 Highlight all hit terms initially

6 and interlayer adj dielectric

BRST... ISAR... Image Text HTML

	U	I	Document ID	Issue Date	Pages	Title	Current OR	Current XRef
1	<input type="checkbox"/>	<input type="checkbox"/>	US 6624473 B1	20030923	55	Thin-film transistor, panel, and methods for producing them	257/344	257/401; 257/408;
2	<input type="checkbox"/>	<input type="checkbox"/>	US 6614052 B1	20030902	28	Semiconductor display devices and applications	257/59	257/350; 257/351;
3	<input type="checkbox"/>	<input type="checkbox"/>	US 6589824 B2	20030708	27	Process for fabricating semiconductor device	438/151	257/E21.134; 257/E21.413;
4	<input type="checkbox"/>	<input type="checkbox"/>	US 6541793 B2	20030401	26	Thin-film transistor and semiconductor device using thin-film transistors	257/57	257/67; 257/E21.413;
5	<input type="checkbox"/>	<input type="checkbox"/>	US 6528820 B1	20030304	21	Semiconductor device and method of fabricating same	257/66	257/347; 257/49;
6	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6331476 B1	20011218	26	Thin film transistor and producing method thereof	438/486	257/E21.413; 257/E21.577;
7	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6326248 B1	20011204	26	Process for fabricating semiconductor device	438/151	257/E21.134; 257/E21.413;
8	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6323072 B1	20011127	36	Method for forming semiconductor thin film	438/166	148/DIG.1; 257/E21.133;
9	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6310363 B1	20011030	24	Thin-film transistor and semiconductor device using thin-film transistors with N and	257/59	257/347; 257/348;
10	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6211535 B1	20010403	15	Method of manufacturing a semiconductor device	257/66	257/65; 257/E21.413;

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